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CONFIRMATION NO. 8829

<b>SERIAL NUMBER</b> 10/820,781	<b>FILING OR 371(c) DATE</b> 04/09/2004 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 2812	<b>ATTORNEY DOCKET NO.</b> 0756-7289
<b>APPLICANTS</b> Shunpei Yamazaki, Setagaya, JAPAN; Koichiro Tanaka, Atsugi, JAPAN; Hidekazu Miyairi, Tochigi, JAPAN;				
<b>CONTINUING DATA</b> ***** <i>none</i>				
<b>** FOREIGN APPLICATIONS</b> ***** <i>not</i> JAPAN 2003-116391 04/21/2003				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 06/19/2004</b>				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met <i>Allowance</i> Verified and Acknowledged <i>Hasetha Date not</i> Examiner's Signature Initials		<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 5	<b>TOTAL CLAIMS</b> 47
			<b>INDEPENDENT CLAIMS</b> 8	
<b>ADDRESS</b> 31780 <i>Where The</i>				
<b>TITLE</b> <i>Method For Manufacturing A Semiconductor Device Having Scanning</i> <i>Beam irradiation apparatus, beam irradiation method, and method for manufacturing semiconductor device</i> <i>Direction</i>				
<b>FILING FEE RECEIVED</b> 1816	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	

*Changes Between Regions*  
*↓ A 11/10/00*  
*During Crystallization Process*